

Supporting Information

Examining Ultramicroelectrodes for Scanning Electrochemical Microscopy by White Light Vertical Scanning Interferometry and Filling Recessed Tips by Electrodeposition of Gold

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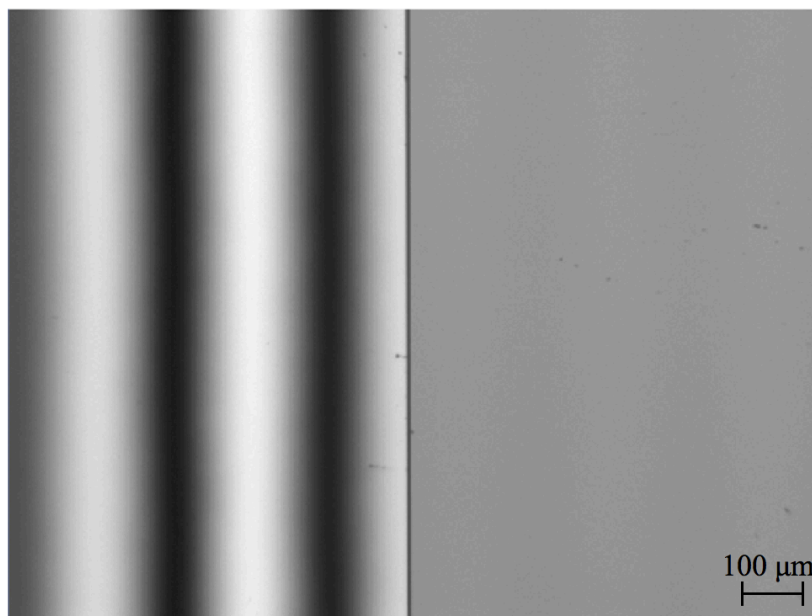


Figure S1. An optical image obtained from the surface profiler of a calibrated silicon step with the left side of the image being the upper portion of the step and the right side of the image being the lower portion of the step. Here the surface profiler is focused on the upper portion of the step and the maximum contrast interference fringes are visible on that section.

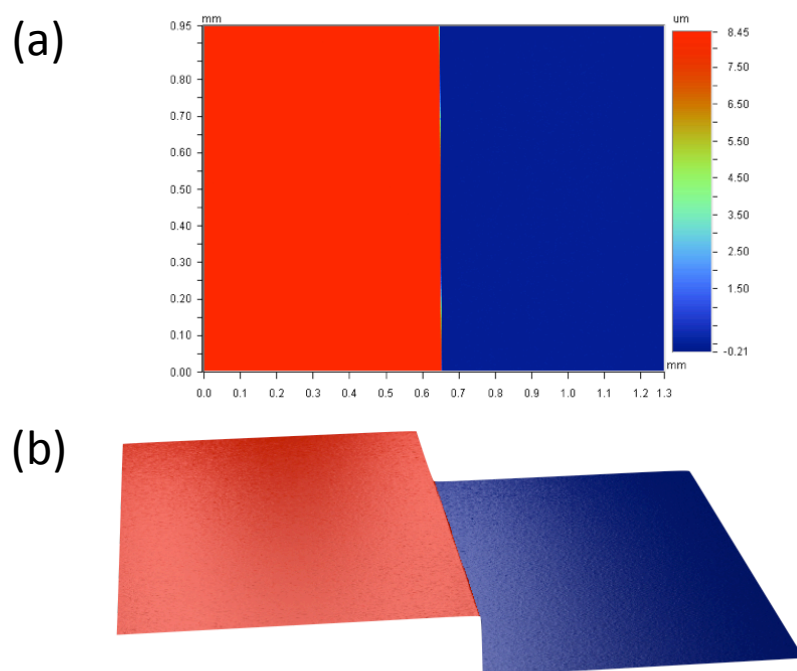


Figure S2. (a) Two-dimensional and (b) three-dimensional surface profile images of a calibrated silicon step obtained using VSI.

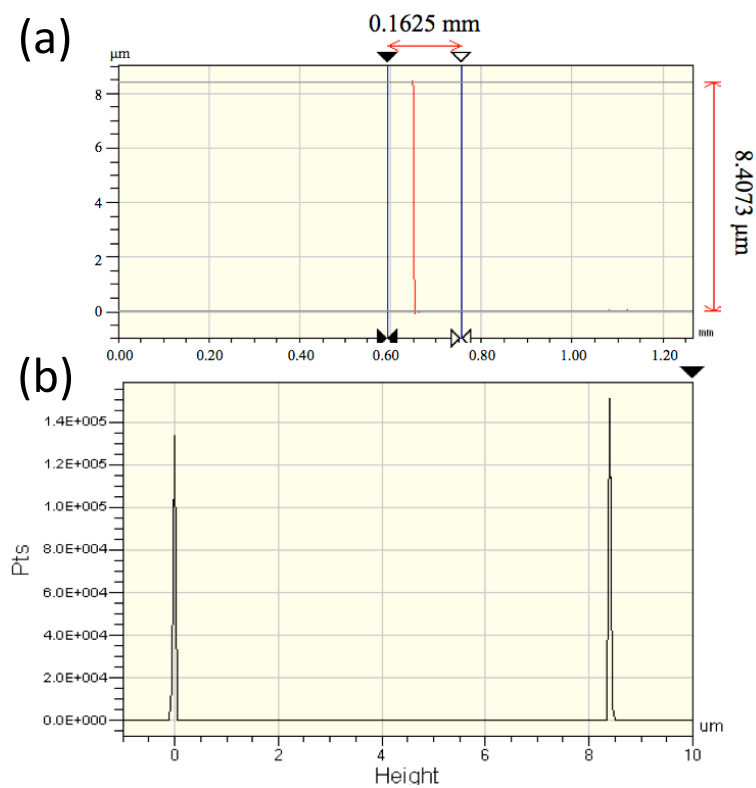


Figure S3. (a) Height profile across a calibrated silicon step with a calibrated height of $8.407 \pm 0.068 \mu\text{m}$ and (b) histogram showing the number of data points as a function of surface height for the calibrated silicon step.